

# Resistive switching behavior in memristors with TiO<sub>2</sub> nanorod arrays of different dimensions

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1   **ABSTRACT:** In this work, memristors based on TiO<sub>2</sub> nanorod arrays (TNAs) were  
2   fabricated using a hydrothermal synthesis method. The memristors had a structure  
3   consisting of a TNA sandwiched between gold and fluorine doped tin oxide (FTO)  
4   coated glass. Devices were constructed using TNAs containing nanorods of different  
5   height, diameter and area ratio, with different oxygen vacancy concentrations. The  
6   devices exhibit resistance switching behavior and the current through the devices is  
7   related to the oxygen vacancy concentration and the area ratio of TNAs. When the  
8   height of nanorods is around 3 μm or less, the devices perform well with a current that  
9   is as low as 10<sup>-8</sup> A in the high resistance state (HRS) and 10<sup>-4</sup> A in the low resistance  
10   state (LRS). It is found that the space charge limited current (SCLC) mechanism  
11   associated with the oxygen vacancies explains the current-voltage behavior of these  
12   devices in this three layer structure. A schematic model is presented to illustrate the  
13   changes in oxygen vacancy concentration and switching processes, including the  
14   formation of new oxygen vacancies (triggered vacancies) to explain the large increase  
15   in current at the end of the setting process in these devices.

16   **KEY WORDS:** Memristors, TiO<sub>2</sub> nanorod arrays, Area ratio, SCLC mechanism.

17

## 1    **Introduction**

2     Titanium dioxide is used many applications in the fields of semiconductors [1],  
3     photo catalysts [2-4], dielectric capacitors[5], paints [6], and dye-sensitized solar cells  
4     [7-9]. Memristor devices based on  $\text{TiO}_2$  show non-volatile and non-linear behavior  
5     and constitute a promising approach to breaking Moore's law and igniting a new  
6     research field [10-12]. The behavior of memristors with a metal/insulator/metal  
7     structure allows for the design of new electronic devices. The stability and  
8     current/voltage properties of such devices suggest a promising future for applications  
9     in large scale intelligent integrated systems, namely bio-synapse emulators products,  
10    resistive random access memory (RRAM) and also as an alternative for flash memory  
11    [13-15]. Novel and stable structures, suitable for memristor devices, have been  
12    extensively researched in the electrical engineering field. Several researchers have  
13    focused their work on metal oxide memristors including  $\text{ZnO}$  [16],  $\text{TiO}_2$  [17],  $\text{HfO}_2$   
14    [18],  $\text{NiO}$  [19], and  $\text{CuO}$  [20]. The active layer structure of memristor devices in  
15    previous research based on  $\text{TiO}_2$  can be mainly separated into cross point and intact  
16    thin films, which both show hysteretic current-voltage (I-V) behavior or analog  
17    switching [21-23]. There are also some investigations on resistive switching  
18    characteristics of  $\text{TiO}_2$  nanowires [24] and  $\text{TiO}_2$  nanorods [25], including  
19    neuromorphic behavior [26]. Unlike thin films fabricated by physical sputtering, for  
20    which post-annealing is needed to introduce oxygen vacancies, hydrothermally

1 fabricated  $\text{TiO}_2$  nanorod arrays (TNAs) contain significant oxygen vacancy  
2 concentrations after low temperature fabrication [14]. The structure of TNAs  
3 produced in this way consists of individual nanorods separated from each other and is  
4 different to the structure of intact films. Generally, beam lithography techniques can  
5 then been used to construct word and bit lines required for memristor devices [27].  
6 After depositing crossbar electrode arrays upon TNAs, another layer can be  
7 synthesized and lapped to fabricate multiple layer devices using a low temperature  
8 hydrothermal process.

9 A number of mechanisms have been proposed to account for the switching behavior  
10 in  $\text{TiO}_{2-x}$  memristors. Szot et al. [12] have classified these broadly into four  
11 catagories, viz: electrochemical where the switching is based on ionic diffusion and/or  
12 change in valency on the cation sublattice [28, 29]; thermochemical involving  
13 formation and rupture of conducting filaments as a result of local temperature changes  
14 [30]; pure electronic where the memristor behaves as a Schottky type diode [13] and  
15 finally the phase change mechanism involving the formation of more highly  
16 conducting Magnèli phases such as  $\text{Ti}_4\text{O}_7$  [12]. Thus mechanisms may involve ionic  
17 and/or electronic transport and be unipolar or dipolar. Devices based on  
18 hydrothermally produced  $\text{TiO}_2$  nanorods ave been shown to have excellent continuous  
19 switching properties [31]. The low temperature synthesis of the TNAs affords are  
20 high concentrations of oxygen vacancies, which can participate in the switching

1 mechanism. For these types of systems, with high vacancy concentrations, a  
2 trap-mediated space-charge-limited current (SCLC) model has been proposed [31].  
3 Electron trapping occurs on the vacancies at the interface between the individual  
4 nanorods, which induces the formation of channels for electron mobility.

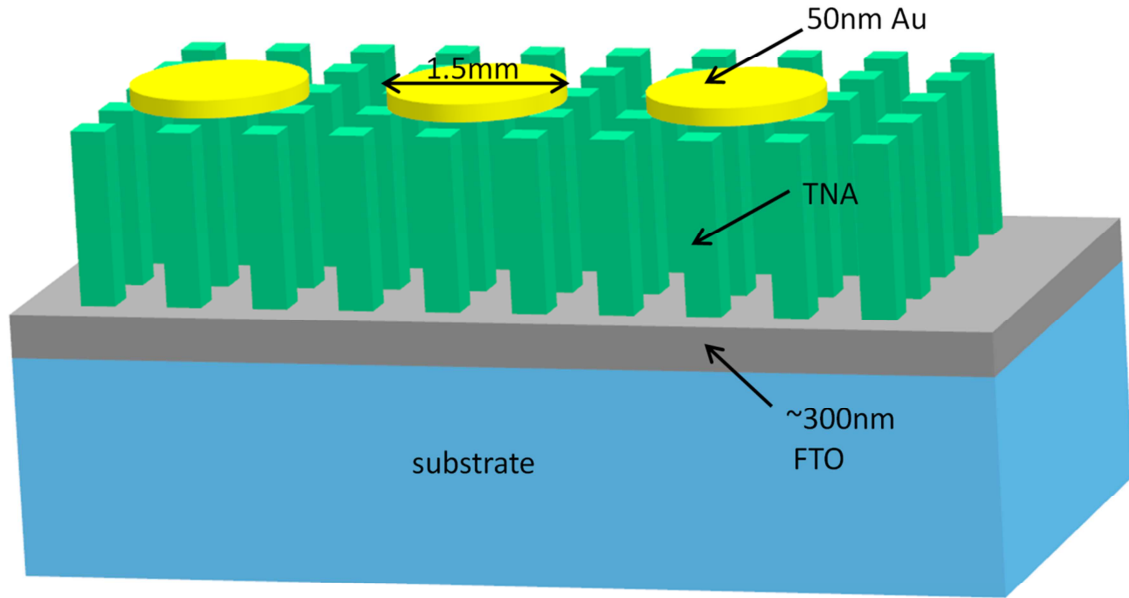
5 To date work on TNA-based systems has focused mainly on the resistive switching  
6 behavior and mechanism, but there has been little reported on the influence of  
7 nanorod dimensions on the intrinsic behavior of these systems. In this work, we seek  
8 to verify the hypothesis that nanorod dimensions can have a significant influence on  
9 memristive behaviour in TNA based devices. We show that nanorod arrays with  
10 different rod dimensions can be readily fabricated using a low cost hydrothermal  
11 method by adjusting the temperature. The hydrothermal process [32-36] is an easier  
12 and more controllable way to obtain well aligned arrays than other techniques, such as  
13 atomic layer deposition [37] and sputtering [38]. This method yields nanorod layers  
14 where the rods are aligned perpendicular to the substrate and the rod dimensions can  
15 be tuned by altering temperature and process duration. Electrical characterization of  
16 memristors constructed from these TNAs is presented and their switching behavior is  
17 discussed in detail, in terms of the space charge limited current (SCLC) hypothesis.

## 18 **Experimental**

19 The TiO<sub>2</sub> nanorod arrays were fabricated by a hydrothermal synthesis process under  
20 a pressurized air atmosphere. Four pieces of fluorine doped tin oxide (FTO) coated

1 glass (supplied by Kaivo Optoelectronic Technology Co., Ltd.) substrate were  
2 successively immersed in acetone, ethyl alcohol, deionized water and were  
3 ultrasonically cleaned thoroughly for 15 min. The clean FTO substrates (blown by  
4 nitrogen gas to remove any surface dust) were located in a 20 ml Teflon sealed  
5 autoclave container with the conductive surface of the FTO leant against the wall of  
6 container. The bath solution consisted of 5 ml H<sub>2</sub>O, 5 ml concentrated HCl (37  
7 w/w%) and 0.238 ml titanium butoxide, which was mixed and stirred for 30 min  
8 before placing in the reactors. The sealed container was placed in an oven and heated  
9 over a period of 25 min to the set temperature. The hydrothermal process employed  
10 four different temperatures (413 K, 433 K, 453 K or 473 K) and held for 2 h to allow  
11 the growth of the TNAs on the glass substrate, before cooling to room temperature  
12 over a period of 120 min. Upon removal from the reactor, each sample was rinsed  
13 with deionized water and blown dry using nitrogen gas.

14 To fabricate the devices, vacuum sputtering (EM SCD 500, Leica) was utilized to  
15 deposit several circle shaped Au spots with a diameter of 1.5 mm on the TNAs  
16 surface (Fig. 1), with an aluminum shadow mask. The duration of deposition was 360  
17 s. Good adhesion of the Au electrodes was found.



1

2 Fig. 1. Schematic diagram of memristor device based on Au/TNAs/FTO.

3 The morphology of the TNAs was examined by field emission scanning electron  
 4 microscopy (SEM, Nova Nano SEM230). Transmission electron microscopy (TEM)  
 5 and high resolution transmission electron microscopy (HRTEM) were carried out  
 6 using an FEI TF20 electron microscope. X-ray diffraction analysis (XRD, Bruker  
 7 Advance D8) was used to analyze the phase and crystal structure of the TNAs with  
 8 Cu-K $\alpha$  radiation ( $\lambda = 1.5418 \text{ \AA}$ ). The surface chemical states of titanium and oxygen  
 9 elements were characterized by X-ray photo-electron spectroscopy (XPS, Thermo  
 10 Fisher Scientific, K-ALPHA). Electrical characterization of the devices was carried

out with an Agilent B1500A analyzer in sweep mode. The bias voltage was applied to the top Au electrode, and the FTO layer was connected with the ground electrode.

## **Results and discussion**

### ***Structural characterization***

TEM images of an individual TiO<sub>2</sub> nanorod are shown in Fig. 2. A HRTEM image and selected area electron diffraction (SAED) pattern of the TiO<sub>2</sub> nanorod are shown as insets in Fig. 2. SEM images of TNAs prepared at the four temperatures used are shown in Fig. 3. The inset images show cross section views of the TNA layers from which the heights of the TNA layers were measured and are listed in Table 1. Each nanorod has a near square profile which grows larger with higher processing temperature and is accompanied a lengthening of the rod. It is evident that a single nanorod is made up of several nanowires of 10-15 nm diameter (Figs 3c and 3d). The shape of the rods is not dependent on the substrate, but on the bath solution [39, 40]. All the nanorods grow on a continuous layer of rutile which facilitates the initial nucleation and controls the density and vertical features. Furthermore, the intertwining of rods can increase the junction surface resulting in electron transfer channels [41, 42]. The average diameter of the nanorods was calculated for a 1  $\mu\text{m}^2$  area as highlighted in Fig. 3. The total number of nanorods in that square was used to



1 calculate the density of nanorods and the area ratio ( $A$ ) of the TNAs was quantified  
 2 using Eqn. 1. All values are summarized in Table 1.

$$3 \quad A = \frac{\sum_{i=1}^n d_i^2}{l \times l} \quad (1)$$

4 where  $d$  is the diameter of a single nanorod, and  $l$  is the length of the highlighted area.

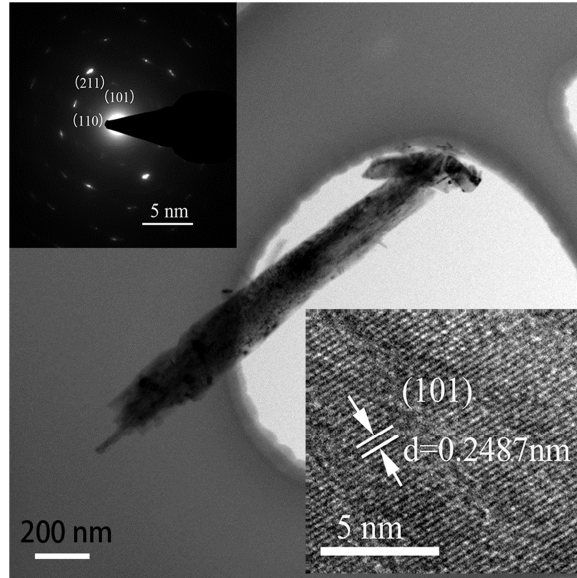
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6 **Table 1.** Nanorod dimensions for TNAs prepared at four different temperatures  
 7 (values are averages from 2 devices and 3 selected regions).

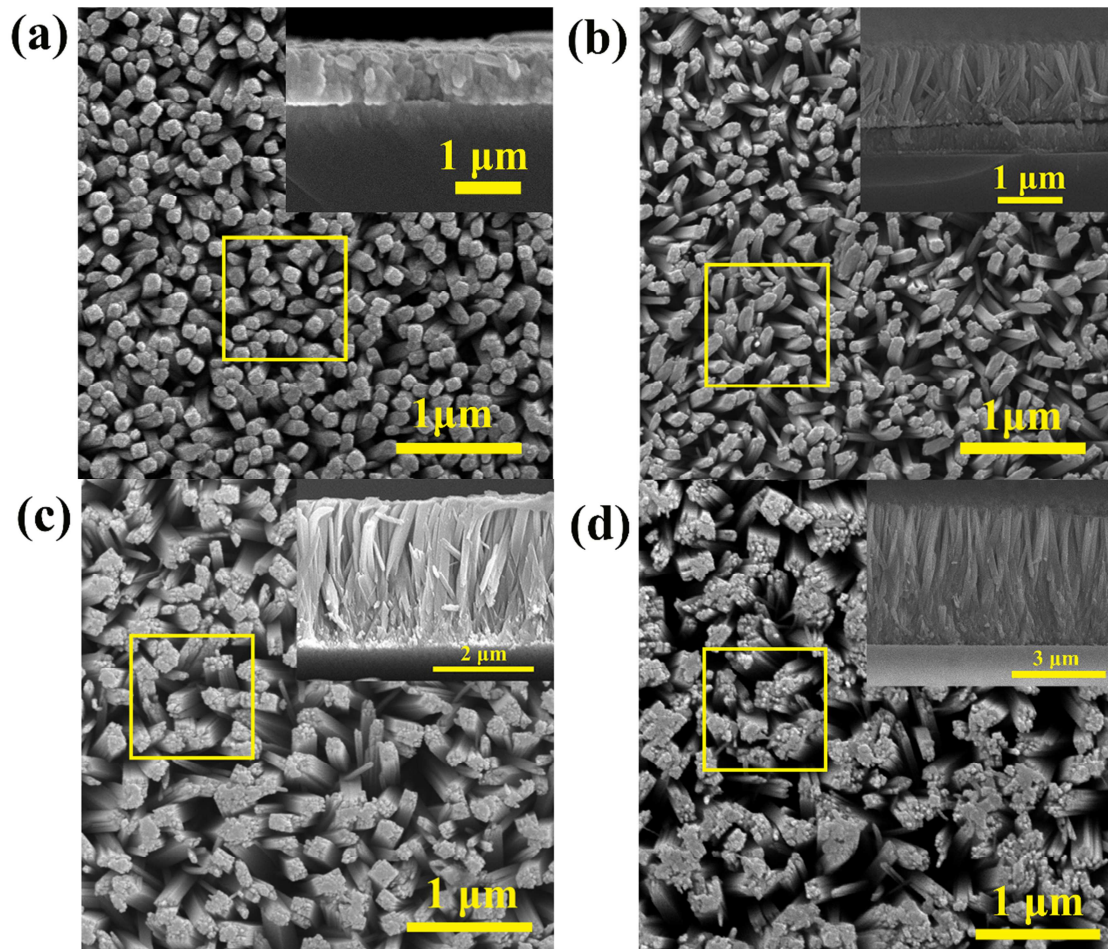
| Temp.<br>(K) | Number of<br>nanorods per<br>$\mu\text{m}^2$ | Average<br>diameter of<br>single nanorod<br>(nm) | Height of TNAs<br>( $\mu\text{m}$ ) | Area ratio<br>(%) |
|--------------|--|--|-------------------------------------|-------------------|
| 413          | 31   | 91   | 0.554                               | 26                |
| 433          | 26   | 91   | 1.210                               | 24                |
| 453          | 15   | 129  | 2.990                               | 27                |
| 473          | 11   | 190  | 4.250                               | 37                |

8

9 The height of the TNAs increases with increasing temperature, because the  
 10 decomposition rate of titanium butoxide at higher temperatures is faster, and the  
 11 nanowire combination and agglomeration is accelerated [43, 44].



1  
2 Fig. 2. TEM images of a single  $\text{TiO}_2$  nanorod (upper inset: SAED pattern of the  $\text{TiO}_2$   
3 nanorod, lower inset: the HRTEM image of the  $\text{TiO}_2$  nanorod).



4

1 Fig. 3. SEM images of four TNAs morphologies, (a) 413K, (b) 433K, (c) 453K, and  
2 (d) 473K. Insets shown in all figures represent the cross section views of the TNAs  
3 layers.

4 Fig. 4 shows XRD patterns of the TNA samples prepared at different temperatures.

5 All the patterns match the standard pattern for rutile ( $\text{TiO}_2$ , JCPDS, no. 21-1276).

6 Weak peaks from the FTO substrate are also visible ( $\text{SnO}_2$ , JCPDS, no. 41-1445).

7 With increasing temperature the peak intensities of the FTO substrate decrease,

8 consistent with the increase in height of the TNAs with increasing temperature. Fig. 4

9 also shows that the  $\text{TiO}_2$  (101) and (002) reflections are enhanced with increasing

10 temperature. This is again consistent with increasing TNA height, with preferred

11 orientation in the diffraction patterns indicating growth of the nanorods along the

12 [001] direction perpendicular to the FTO substrate. These results agree with similar

13 synthesis work in solar cell research [44].

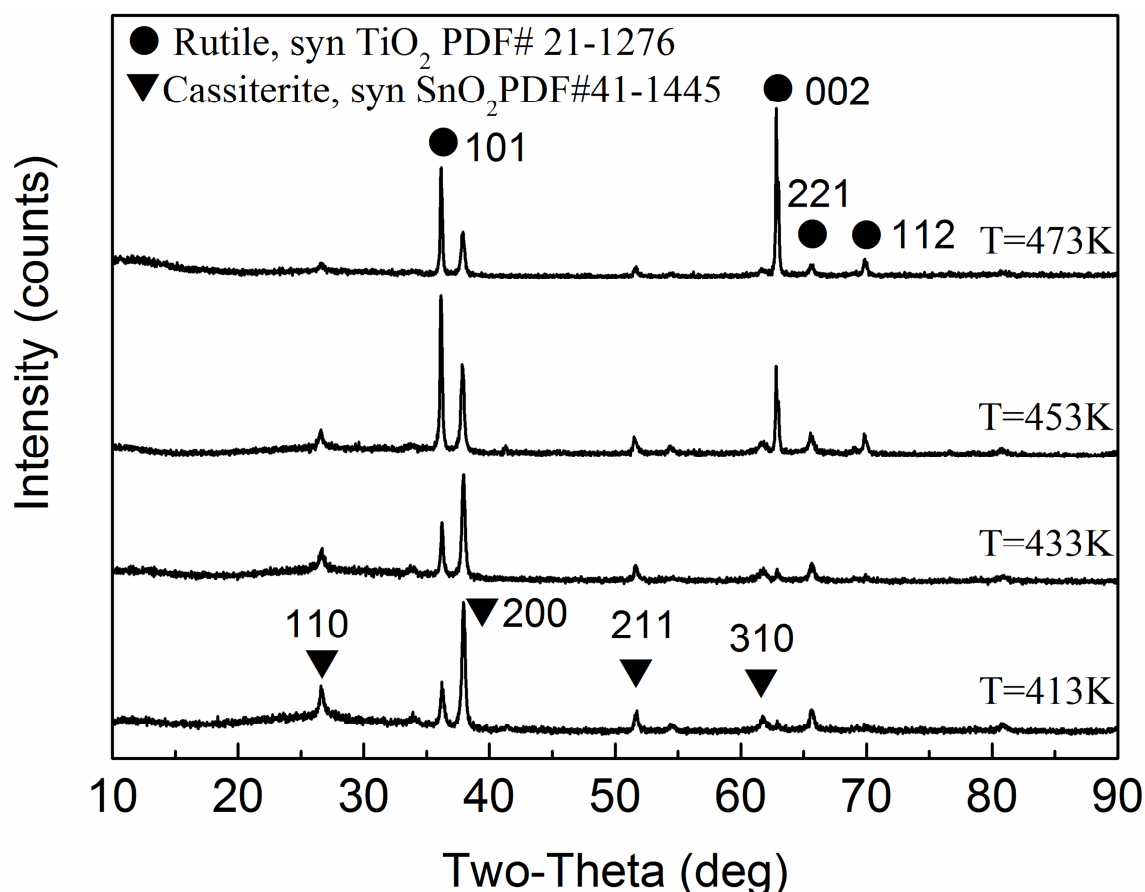
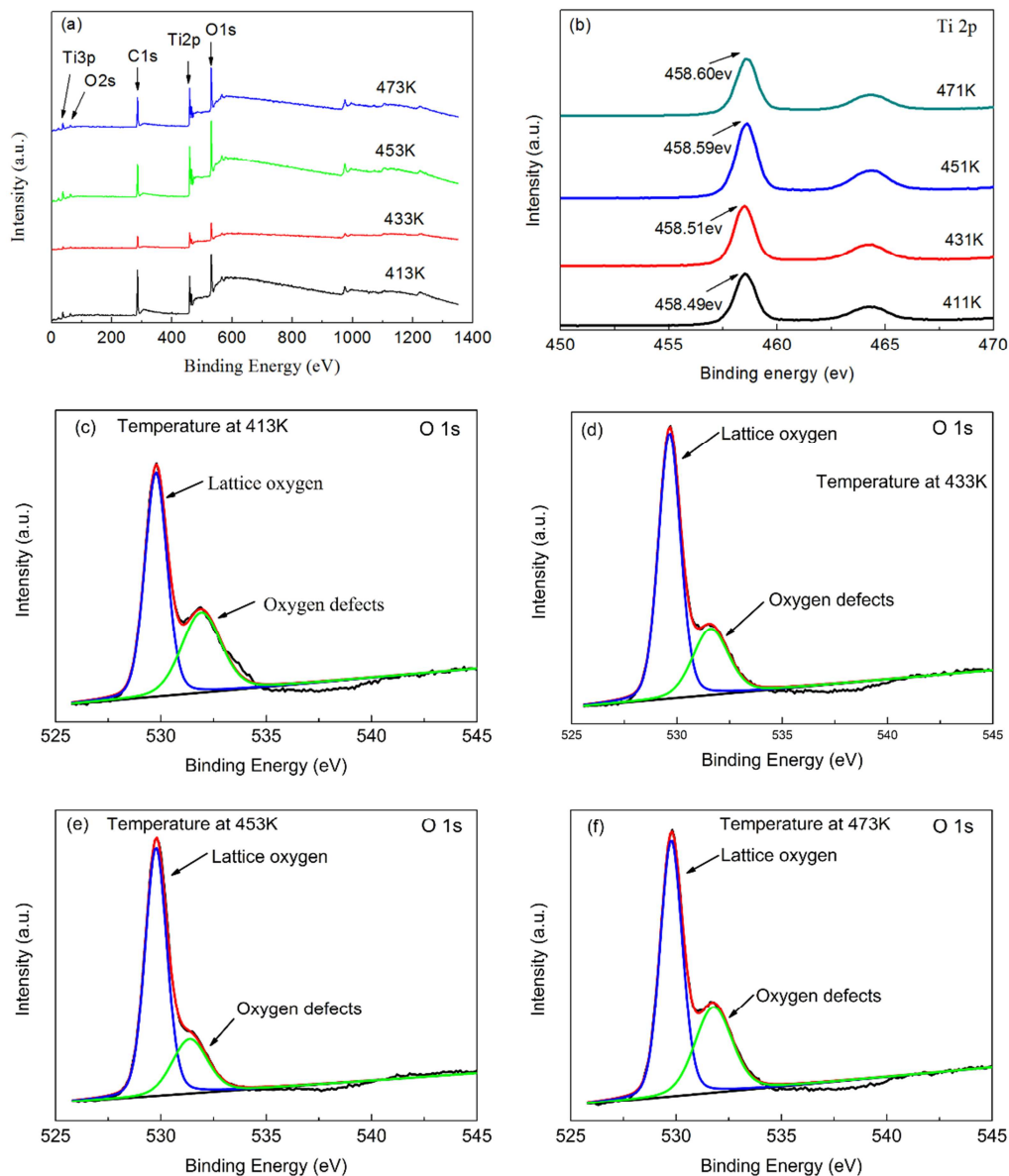


Fig. 4. XRD patterns of TNA layers synthesized at different temperatures on FTO glass substrates.

The chemical states of the TNA surfaces were investigated by XPS. The XPS survey spectra for TNA samples prepared at 413 K, 433 K, 453 K, and 473 K are shown in Fig. 5a. The patterns verify the presence of Ti, O and C (the latter from air contamination). High resolution XPS spectra covering the Ti 2p peaks are given in Fig. 5b. The Ti  $2p_{1/2}$  (higher binding energy) and  $2p_{3/2}$  (lower binding energy) peaks are evident with a separation of 5.7 eV. The Ti  $2p_{3/2}$  binding energy of around 458.6 eV is in agreement with literature reported on  $\text{TiO}_2$  [31], and is seen to increase with

- 1 increasing reaction temperature. This would be consistent with a small degree of Ti
- 2 reduction to  $\text{Ti}^{3+}$  at higher reaction temperatures.



3

4 Fig. 5. XPS spectra of TNA layers synthesized at different temperatures showing (a)

5 full survey spectra; (b) high resolution spectra for Ti 2p; high resolution spectra for

6 O1s and the fitted spectra, (c) at 413 K, (d) at 433 K, (e) at 453 K and (f) at 473 K.

7

1 The high resolution O 1s spectra were fitted by two Gaussian peaks (see Figs.  
2 5c-5f). The peak located at lower binding energy (529.7 eV) represents the lattice  
3 oxygen (i.e. oxygen bound to  $\text{Ti}^{4+}$ ), while the other peak (531.2 eV) is attributed to  
4 oxygen defects on the nanorod surface [45], i.e. those oxygen atoms bound to  $\text{Ti}^{3+}$   
5 [46], which is directly proportional to the number of oxygen vacancies. The peak  
6 position of the Ti-O bond shifts to higher energy as the synthesis temperature  
7 increases from 413 K to 473 K, which suggests the chemical state of Ti or O atoms  
8 change. The percentage of oxygen defects (listed in table 2), calculated according to  
9 the peak area and impact sensitivity factor [47], decreases with increasing synthesis  
10 temperature up to 453 K, followed by a significant increase at 473 K. This trend in  
11 oxygen defect concentration is related to the area ratio of the TNAs.

12  
13 **Table 2.** The percentage of oxygen defects and lattice oxygen calculated from the  
14 XPS data.

| Temperature (K) | Percentage (%)                    |                                       |
|-----------------|-----------------------------------|---------------------------------------|
|                 | Lattice oxygen ( $\text{TiO}_2$ ) | Oxygen defects ( $\text{TiO}_{1.5}$ ) |
| 413             | 61.26                             | 38.74                                 |
| 433             | 71.44                             | 28.56                                 |
| 453             | 73.89                             | 26.11                                 |
| 473             | 64.07                             | 35.93                                 |

15

16 ***Electrical chracterization***

1 For the electrical tests, the deposited gold served as the top electrode and the FTO  
2 as the grounded bottom electrode. Current-voltage (I-V) hysteresis loops of devices  
3 based on the TNA layers prepared at different temperatures are shown in Fig. 6, with  
4 the semi-logarithmic I-V characteristics inset (further cycles are given in the  
5 supporting information as Fig. S1). The devices are denoted S1, S2, S3 and S4 for  
6 those TNAs prepared at 413, 433, 453 and 473 K, respectively. All four devices  
7 display bipolar resistive characteristics over the range -4 V to 2 V. Device S4 shows  
8 an I-V loop more typical of  $\text{TiO}_x$  devices, while those for devices S1, S2 and S3 are  
9 quite different [11, 37]. For device S1 (Fig. 6a), as the voltage firstly sweeps from 0 to  
10 -4 V, three ranges in the current curve can be defined. In the first range, from 0 to  
11 -1.29 V, the response current maintains a near constant value. From -1.29 V to -2.27  
12 V, an exponential increase in current is observed. In the final step (-2.27 V to -3.46  
13 V), the current increase is sharper until reaching the compliance current of 1 mA at  
14 -3.46 V. On reversing the voltage from -4 V to 0, the current continuously decreased  
15 from  $10^{-4}$  A to  $10^{-6}$  A. The results are similar for the other three devices, though the  
16 strength of current and the area of the hysteresis loop are different.

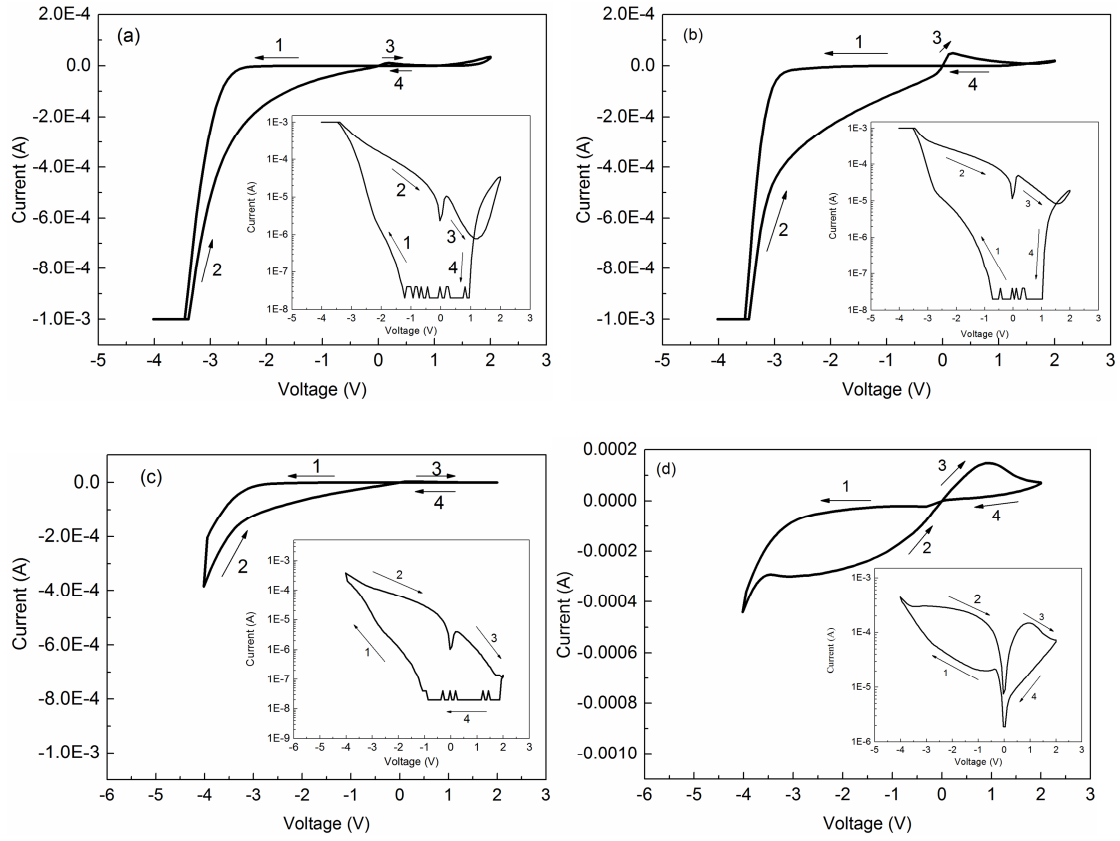


Fig. 6. Typical hysteresis I-V curves of Au/TNAs/FTO devices containing TNAs synthesized at: (a) 413 K (S1), (b) 433 K (S2), (c) 453 K (S3) and (d) 473 K (S4). Semi-log I-V curves are inset.

The current at -3 V during the setting process (0 to -4 V) and the voltage at which the devices transform from the high resistance state (HRS) to the low resistance state (LRS, resistance < 100 k $\Omega$ ) are listed in Table 3. The current values at -3 V on setting are found to decrease with increasing temperature of TNA synthesis, while the voltage values at which the devices reach the LRS increase with increasing temperature of TNA synthesis. In the case of the device S4, the current at -3 V was higher than that for devices S2 and S3 and it was at the LRS throughout the measurement. As seen in Table 1, the TNA area ratios decrease with increasing



1 reaction temperature from 413 K to 453 K and would be consistent with the  
2 decreasing current at -3 V.

3 The observed electrical behavior can be explained by considering the changes in  
4 oxygen vacancy concentration. With increasing temperature of the hydrothermal  
5 process, the concentration of oxygen defects decreases up to 453 K, and is correlated  
6 with the observed decrease in current for the set process of devices S1, S2 and S3.  
7 Oxygen vacancies play an important role in the conduction of materials [12], acting as  
8 electron traps and allowing for the formation of conducting channels. The current at  
9 -3 V for the device S4 is seen to increase with respect to that for device S3, consistent  
10 with the observed increase in oxygen defect concentration between TNAs prepared at  
11 473 K and 453 K (Table 2). However, despite the similarities in defect concentration  
12 between the samples prepared at 413 and 473 K, the devices based on these TNAs  
13 show very different currents at -3 V. This suggests that not only is defect  
14 concentration an important factor, but that the resistance associated with TNA height  
15 is also a significant factor. Indeed previous studies on thin films have shown that film  
16 thickness is inversely related to current [23]. In the present work this relationship is  
17 also found in devices S1 to S3. However, in the case of device S4, which has the  
18 tallest nanorods, the current increases slightly due to the increase in oxygen vacancy  
19 concentration. Additionally, device S4 exhibits poor switching behavior with only a  
20 small difference between LRS and HRS. The results suggest that oxygen vacancy

concentration is the primary factor responsible for the set current and that a TNA height of around. 3  $\mu\text{m}$  or less is required for significant bipolar switching.

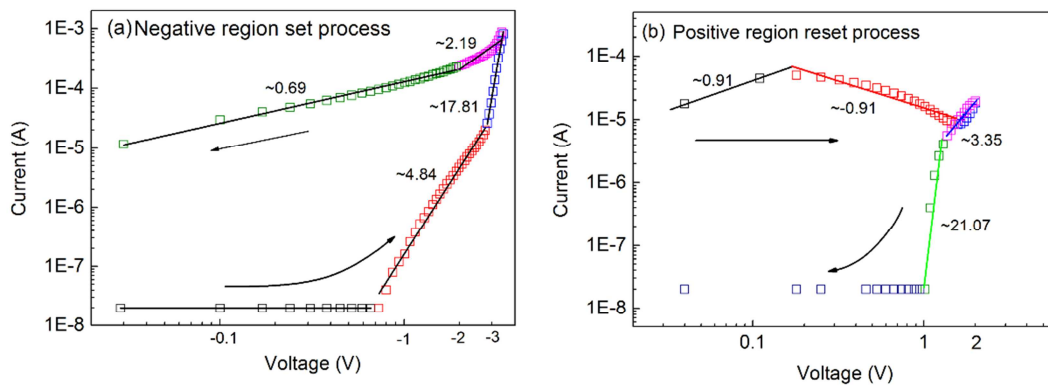
**Table 3.** The current at -3 V during the setting process (0 to -4 V) and the voltage at which devices S1 to S4 transform from high resistance state (HRS) to the low resistance state (LRS, resistance < 100 k $\Omega$ ). Values are averages from 2 devices.

| Samples | The current value when the voltage is -3 V (A) | The voltage value when the resistance is reduced to 100 k $\Omega$ (V) |
|---------|--|--|
| S1      | $22.06 \times 10^{-5}$                         | -2.62  |
| S2      | $5.61 \times 10^{-5}$                          | -2.90  |
| S3      | $1.31 \times 10^{-5}$                          | -3.25  |
| S4      | $8.30 \times 10^{-5}$                          | -  |

Based on the resistive switching behavior, several popular mechanisms can be used to fit the domain current, corresponding to applied voltage or electric field. These mechanisms include, (i) Poole-Frenkel emission [48]; (ii) Schottky emission [49]; (iii) space charge limited current (SCLC) [50, 51] and (iv) Fowler-Nordheim Tunneling [52]. Since the memristors in the current work are based on TNAs with abundant oxygen defects, the SCLC mechanism can be used to explain the I-V loops. This mechanism has been used to account for the conduction mechanism in other TNA

1 based sandwich structures [31]. In the SCLC mechanism, oxygen vacancies act as  
 2 electron traps, which can diffuse through the material and trigger the formation of  
 3 further oxygen vacancies under an external applied voltage [53].

4 The retention time in HRS and LRS of the 4 devices was measured and is shown in  
 5 the supporting information in Fig. S2. In HRS the retention times for all devices are  
 6 above 2000 ms. For the devices S1, S2 and S3, the LRS retention time decreases with  
 7 decreasing oxygen vacancy concentration and increasing nanorod height. It is  
 8 reported that long retention times are associated with potential wells or deep traps  
 9 which prevent the trapped electrons escaping [54]. Device S4 exhibits the longest  
 10 LRS retention time. The TNAs in the device exhibited defect concentrations similar to  
 11 those in device S1, but with a much larger area ratio. The results show that the  
 12 relationship between retention time, area ratio and oxygen vacancy concentration is  
 13 complicated.



1 Fig. 7. Fits to  $\log(I)$ - $\log(V)$  curves of the S2 device based on TNAs synthesized at  
2 433 K, using the SCLC model, showing (a) the set process and (b) the reset process.  
3 Fitted slopes are indicated.

4

5 The fitted  $\log(I)$  vs  $\log(V)$  curves for the S2 using the SCLC model are shown in Fig.  
6 7. When the voltage sweeps from 0 to -4 V, the curve shows three steps as described  
7 above and can be fitted to lines of different slope. While the negative voltage carried on  
8 the top electrode is small (less than 0.73 V in this case), the Schottky barrier at the  
9 Au/TNA interface constrains the electron transport, which is caused by the difference  
10 between the work function of the Au top electrode (5.1 eV) and the Fermi level of rutile  
11  $\text{TiO}_2$  (4.2 eV). The Fermi level of the interface is closer to that of rutile. The barrier  
12 limits the diffusion of electrons and oxygen vacancies. So the device shows a small  
13 rectifying current and stays in the HRS. The initial process is associated with the Ohmic  
14 contact and the current is attributed to the thermally generated free carriers [55]. Lattice  
15 vibrations caused by Joule heating and long electron diffusion distances could explain  
16 the low current observed in the studied device. When the sweep voltage is higher than  
17 the threshold voltage in the trap filled limiting region, the current significantly  
18 increased in response with a slope much greater than 2.0 (the theoretical value from  
19 Mott's Law) in the  $\log(I)$ - $\log(V)$  plot. This type of deviation from Mott's law in the  
20 transition region has been previously been attributed to the dynamic evolution of  
21 oxygen vacancies under bias polarization [56, 57]. The filled traps create channels for

1 rapid electron transport. After the first channel is generated, further traps are filled and  
2 the device switches from HRS to LRS. At the end of the set process, there is an  
3 acceleration of trap filling, which is attributed to the triggering of new vacancies. Under  
4 a high enough bias, new vacancies are triggered and act as additional traps to enlarge  
5 the conducting channels and increase the current [58]. When the voltage was swept  
6 from -4 V to -1.92 V, the slope of  $\sim 2.19$  in the  $\log(I)$  vs  $\log(V)$  plot suggests that the  
7 traps remain virtually fully filled. As the voltage was swept from -1.92 V to 0 V, the  
8 slope was 0.69 and a resistance of around  $10^4 \Omega$  was maintained (LRS). In the reset  
9 process, initially a slope of nearly 1 is observed up to 0.18 V, confirming traps are filled.  
10 Above 0.18 V the slope is reversed as electrons flow from the traps and the device  
11 gradually switches from LRS to HRS. At higher voltages up to 2 V a large slope of 3.35  
12 is seen, indicating that the negative bias carried on the Au top electrode forces the  
13 electrons to leave the traps more rapidly as more traps empty. As the voltage is reduced,  
14 the device in its HRS state forces a sharp reduction in current, until reaching an almost  
15 constant current at around 1 V. On reversing the bias, electrons are transported from the  
16 bottom FTO electrode to top the Au electrode, and the filled traps lose their electrons  
17 and become barriers again. Eventually, the device returns to its initial HRS state.

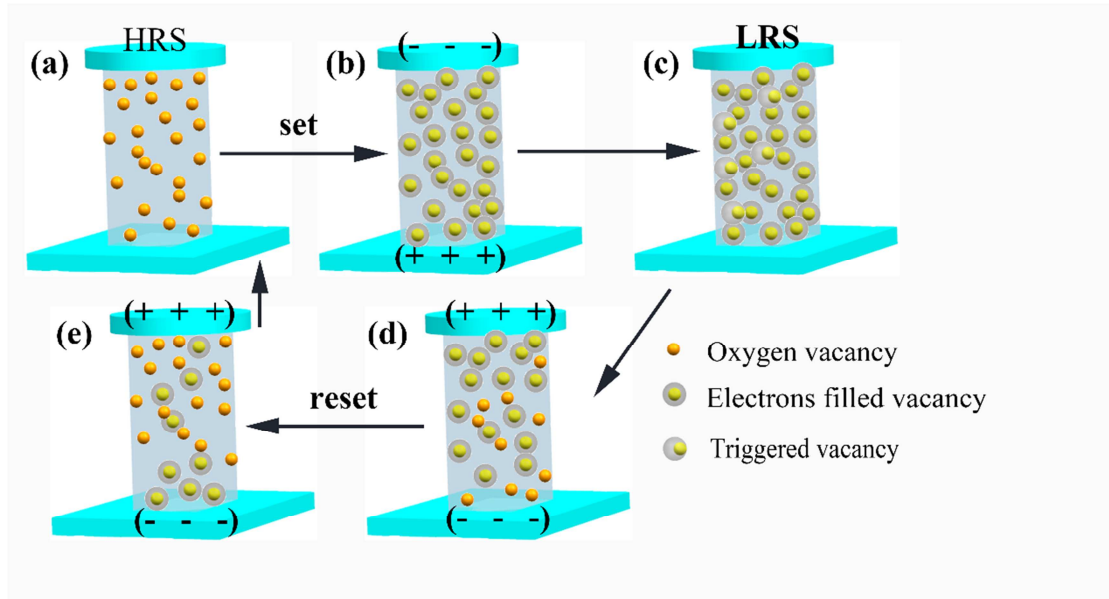


Fig. 8. Schematic diagram showing changes in electron trapping by oxygen vacancies during set and reset processes in Au/TNA/FTO memristor devices.

A schematic model for the electron trapping behavior in the studied devices based on the SCLC mechanism is shown in Fig. 8. As can be seen in Fig. 8a, the initial state of the device is in HRS and the oxygen vacancies of the as prepared TNAs are distributed randomly. When a small bias (either negative or positive) is applied on the top Au electrode, the device possesses a very small rectifying current in the order of 10 nA. Although the tiny bias is not enough to switch the resistance state of the device, there is a small potential gradient and gradually this overcomes the interface Schottky barrier and forces the electrons to fill the oxygen vacancies. Here the oxygen vacancies act as traps and can be regarded as electron reservoirs which can transform from the empty state (lack of electrons) to the full state (filled electrons) [23]. It is noted here that the oxygen vacancies themselves are unlikely to show significant

diffusion. As the oxygen vacancies become filled with electrons they form channels through which current can flow, increasing rapidly, with more vacancies around the channel becoming filled (Fig. 8b). In addition, the filled traps can trigger formation of new vacancies, enhancing the conduction channel. This results in a sharp increase in current in the later period of the setting process. This phenomenon can be readily understood using a simple analogy of a stream flowing through a channel, as the flow of water increases, the banks of the channel are eroded and collapse, widening the channel and increasing the flow. After most of the intrinsic vacancies are filled by electrons, the device switches to the LRS and with Ohmic contact behavior (Fig. 8c). On reversing the bias, filled vacancies away from the channels can release electrons preferentially. However, the diffusion distance is such that they make little impact on the current, with values in the order of  $10^4 \Omega$ . In the case of a positive bias, triggered and intrinsic vacancies empty successively (Fig. 8d). The conductive channels of traps become disrupted and the de-trapping process is accelerated (Fig. 8e). When most of the vacancies recover to their empty state, the device returns to HRS and exhibits a small rectifying behavior (Fig. 8a).

## Conclusions

Bipolar memristor devices of the type Au/TNA/FTO with different TNA morphologies were prepared and investigated. The height and area ratio of the TNAs were found to affect oxygen vacancy concentration and in turn memristive behavior.

1 The area ratio of the TNAs decreased with increasing synthesis temperature from 413  
2 K to 433 K, but then increased at 473 K, while the oxygen defect concentration  
3 decreased with increasing TNA height up to around 3  $\mu\text{m}$ . Devices based on TNAs of  
4 this height or less showed good memristive performance, while those containing  
5 TNAs of 4.25  $\mu\text{m}$  showed little difference between the low resistive and high resistive  
6 states. The current-voltage behavior of these TNA based devices was investigated in  
7 detail and explained by the SCLC mechanism. A small rectifying current is observed  
8 under small bias. A large increase in current at the end of the setting process is  
9 attributed to the creation of new vacancies (triggered vacancies).

## 10 **Conflicts of interest**

11 There are no conflicts of interest to declare.

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